

In re Application of:
Yuxiang M. Wang, et al.

Group Art Unit: 1765

Examiner: Maki A. Angadi

For: Method of Depositing an Amorphous Carbon Film for Metal Etch Hardmask Application

MAIL STOP AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

I hereby certify that this correspondence is being electronically transmitted to the U.S. Patent and Trademark Office via EFS-Web to the attention of Examiner Maki A. Angadi, on the date shown below.

July 23, 2007
Date

Keith M. Tackett

Dear Sir:

RESPONSE TO FINAL OFFICE ACTION DATED MAY 23, 2007

In response to the Final Office Action dated May 23, 2007, having a shortened statutory period for response set to expire on August 23, 2007, please enter this response and reconsider the claims pending in the application for reasons discussed below. Although Applicants believe that no additional fees are due in connection with this response, the Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/008245/KMT, for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

The **Claims** are reflected in the listing of claims which begins on page 2 of this paper. **Remarks** begin on page 7 of this paper.